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Electrical characteristics of devices using the IVCharacteristics study object

Electrical characteristics of devices using the IVCharacteristics study object

Version: U-2022.12

Downloads & Links

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- [IVCharacteristics](#)
- [Study objects](#)
- [soi_device_configuration.py](#)
- [Workflow 1](#)
- [Workflow 2](#)
- [Workflow 3](#)
- [soi_device_ivc_through_scripting.py](#)

This tutorial introduces the [IVCharacteristics](#) **study object** used within the framework of the **Workflow Builder**. The [IVCharacteristics](#) study object enables the calculation and analysis of the most relevant electrical characteristics of field-effect transistor (FET) device models, including the on/off ratio ($I_{\text{on}}/I_{\text{off}}$), the subthreshold slope (SS), the transconductance (g_m) and the drain-induced barrier lowering (DIBL) ^[1].

In the present tutorial, you will learn how to use [IVCharacteristics](#) study object in the **Workflow Builder** to setup, calculate and analyze some of the electrical characteristics of a model silicon-on-insulator (SOI) device. These workflows will be demonstrated for a preconstructed SOI FET device modeled with the [DeviceSemiEmpiricalCalculator](#) adopted for the [IVCharacteristics](#) study object to calculate the SS, and DIBL parameter values and then benchmark them against the available experimental data.

Prerequisites

A general knowledge of the charge carrier transport in microelectronics devices and related IV characteristics is expected, e.g., IV curve, on/off ratio, subthreshold slope, transconductance, and drain-induced barrier lowering. If you are not familiar with these concepts you can still learn from this tutorial, but will not get the full benefit. If you wish to learn about them, we recommend reading this paper: ^[1].

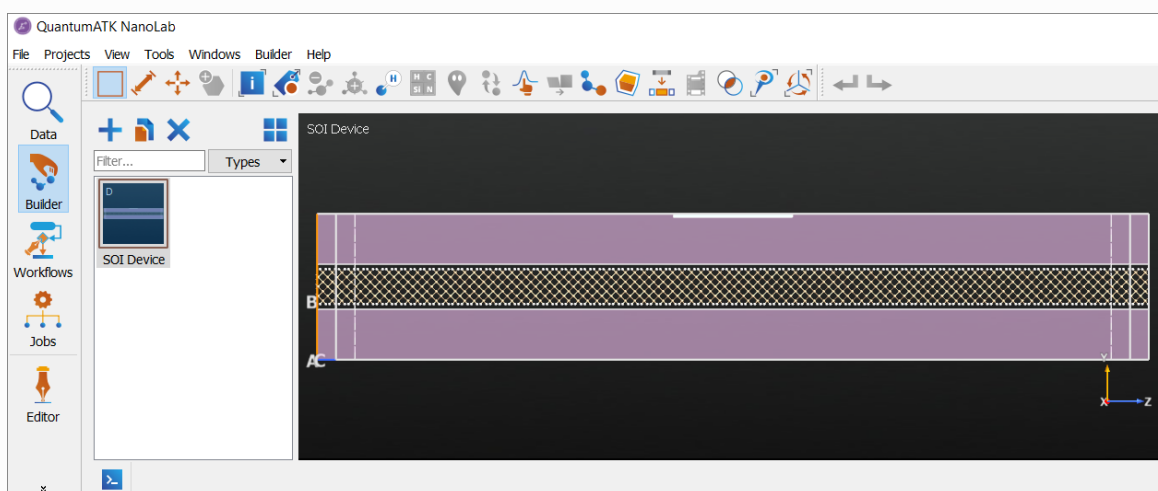
Tip

This tutorial is designed to require no previous experience with the QuantumATK interface, but if you wish to better understand the basics, please see the introductory tutorial here: [How to use QuantumATK for fast and easy atomic scale modelling](#).



Calculation and analysis of the $I_{ds} - V_{gs}$ curve for the FET on-state

The SOI FET device model structure considered in the tutorial is shown in the figure below. It consists of a hydrogen-passivated 2D silicon slab, which includes a Si channel region connected with an ideal contact to source and drain leads made of highly-doped Si; two continuum dielectric regions acting as the SiO_2 dielectric substrate or spacer (with $\epsilon = 3.9\epsilon_0$) between a continuum metal gate and atomistic Si channel region.

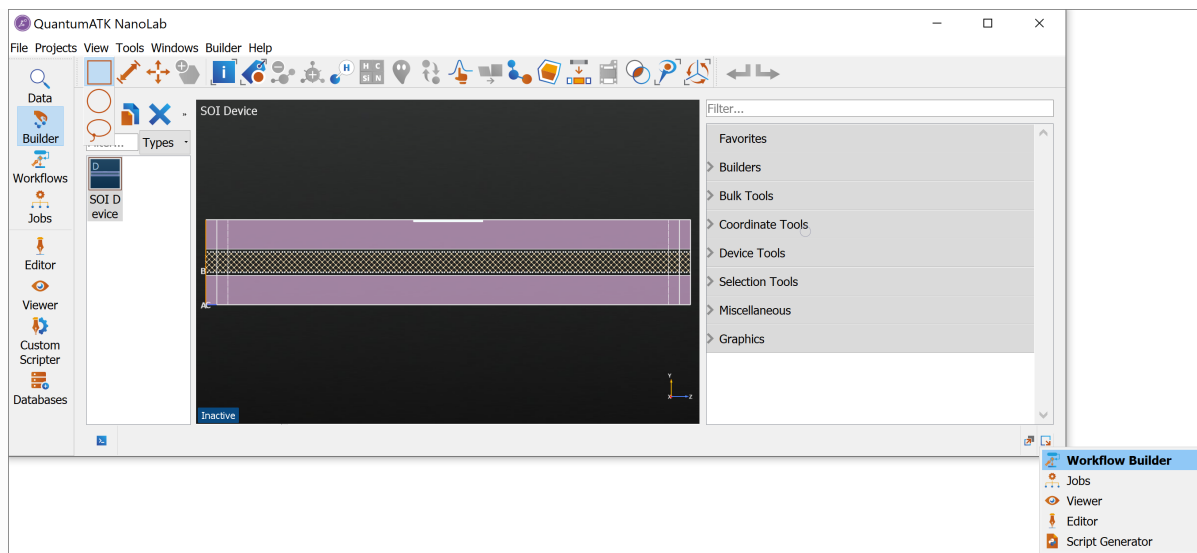


For the sake of computational efficiency, the electronic structure of the device model will be calculated using a semi-empirical tight-binding model [2].

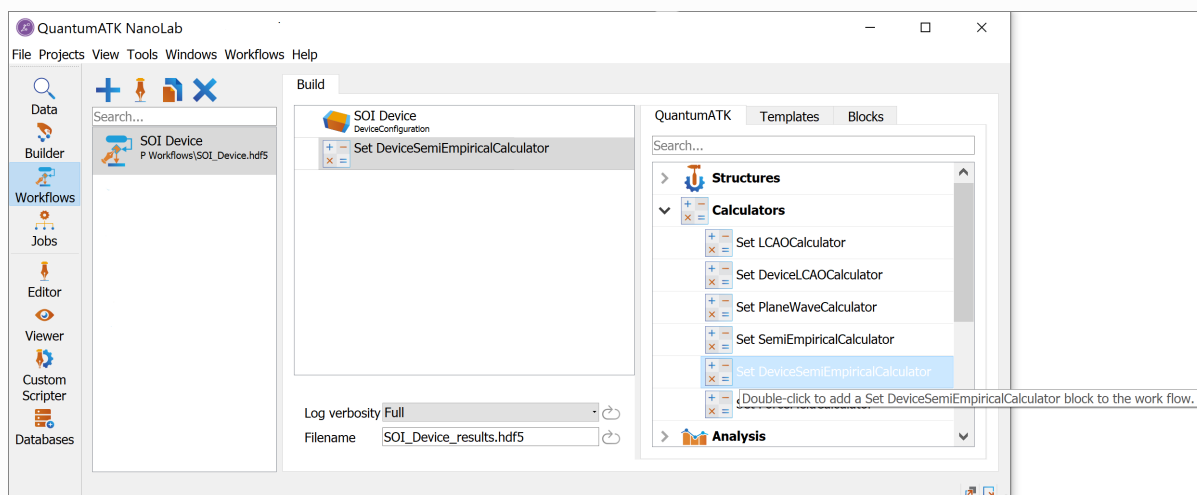
Setting up a Workflow

To create a workflow for `IVCharacteristics` calculations in the **Workflow Builder**, follow the step-by-step protocol described below. For a general introduction to the **Workflow Builder**, please see the dedicated guide: [Introduction to the Workflow Builder](#).

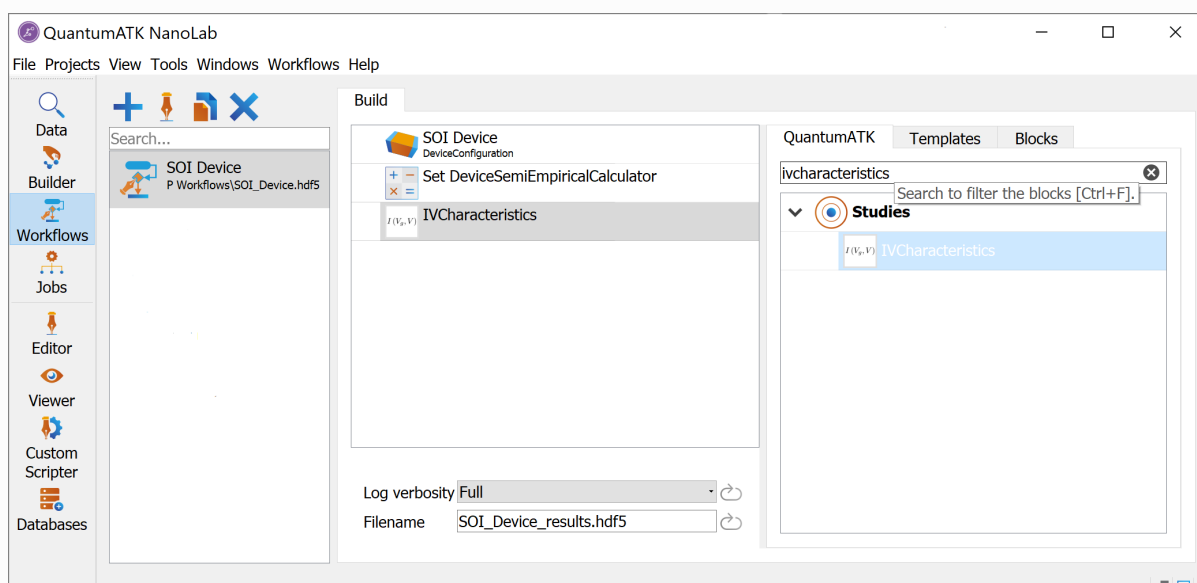
- To add the SOI FET device configuration (shown in the previous figure) to the **NanoLab Builder**, download the script `soi_device_configuration.py`, and drag-and-drop it on to the **NanoLab Builder** icon from the **Data View**. Or use the **Add** button in the **NanoLab Builder** to import the device structure from the script `soi_device_configuration.py`.
- In the **NanoLab Builder**, send the SOI `DeviceConfiguration` to the **Workflow Builder**.



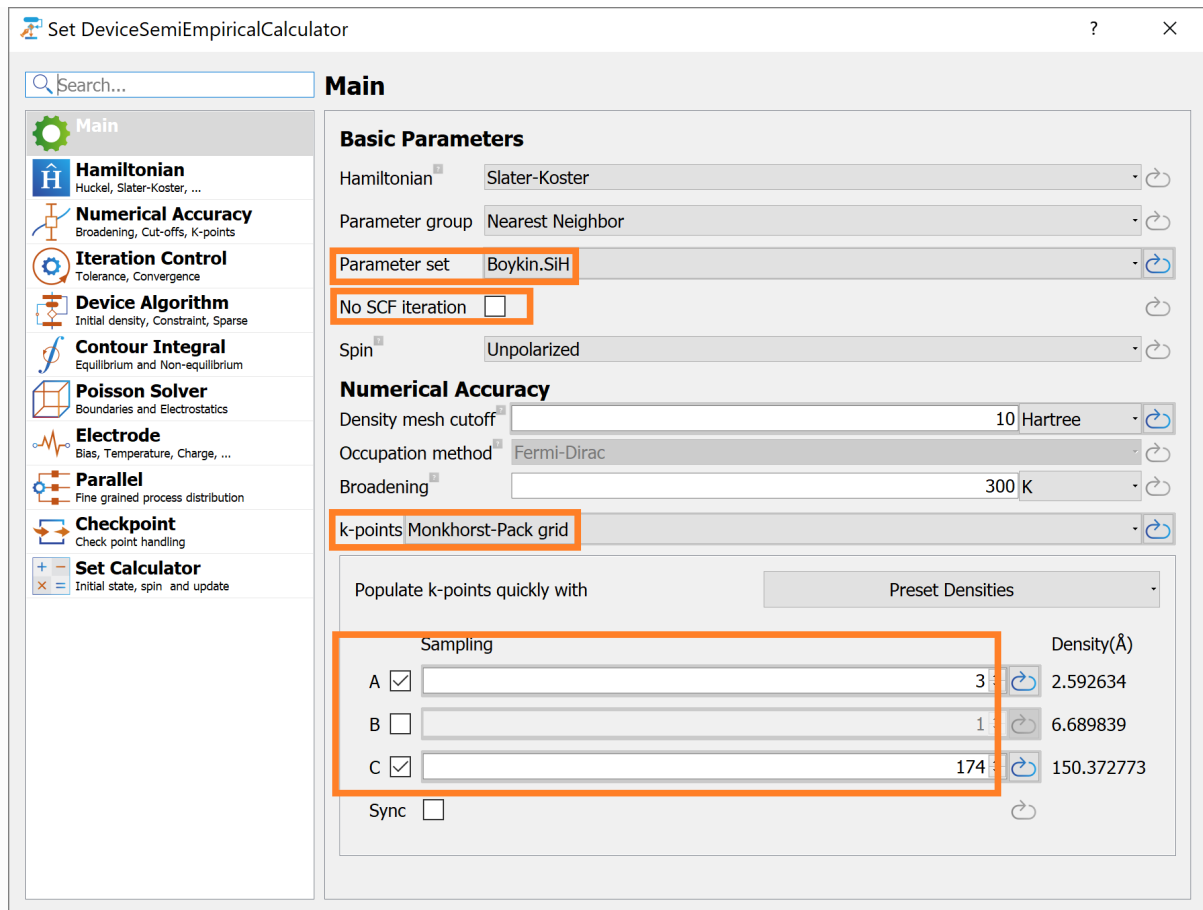
- In the Workflow Builder window, add a *Set SemiEmpiricalCalculator* to the *SOI Device* workflow.



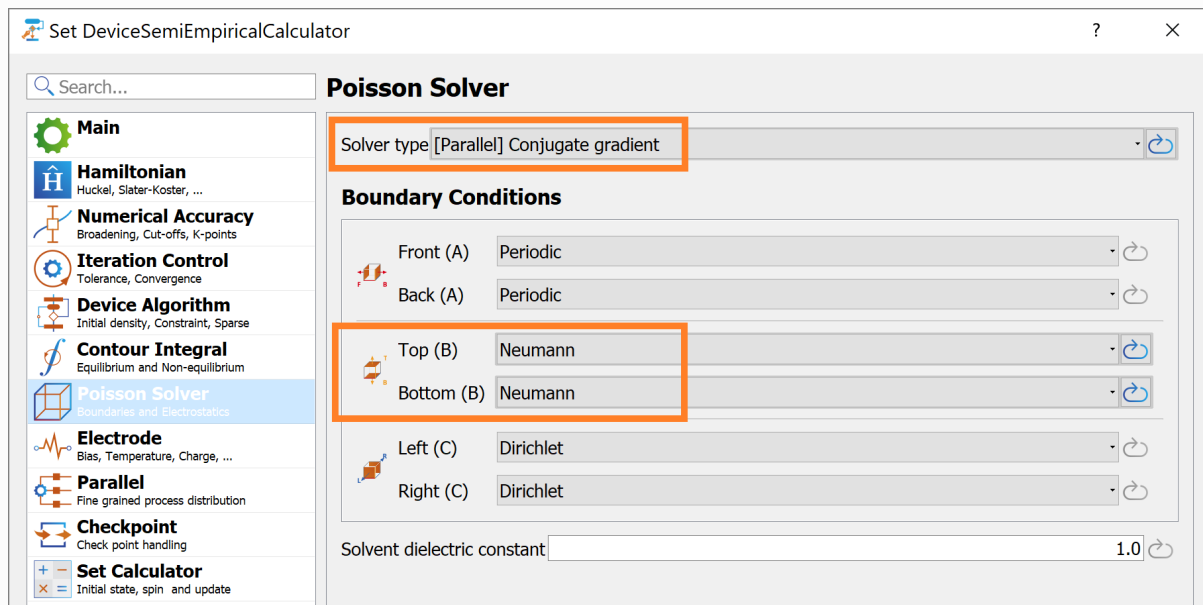
- In the QuantumATK Search bar, type *ivcharacteristics* to find the corresponding $I(V_g, V)$ *IVCharacteristics* study object and then add it to the workflow by double-clicking.



- In the Main section of the *Set SemiEmpiricalCalculator* block, change the *Parameter* set to *Boykin.SiH*, uncheck the *No SCF iteration* box, change *k-points* from *Density* to *Monkhorst-Pack k-grid*, and set the *k-point sampling* to 3x1x174.



- Change the **Poisson Solver** settings of the **Set SemiEmpiricalCalculator** block by switching to the **[Parallel] Conjugate gradient** Poisson solver, and set the top and bottom boundary conditions (in the B-direction) to Neumann, because there exists no periodicity in the direction perpendicular to the Si slab surfaces.



- Edit the $I(V_g, V)$ **IVCharacteristics** settings in the workflow to set a range of gate voltage values for calculating the $I_{ds} - V_{gs}$ curve.

IVCharacteristics

Basic Parameters TransmissionSpectrum Analysis

Log filename prefix

Processes per task

Gate regions

Gate source voltages

V_{gs0}

V_{gs1}

Points

Unit

Drain source voltages

V_{ds0}

V_{ds1}

Points

Unit

Gate potential alignment

Reference_electrode

Use intrinsic chemical potential ☐

Work function difference

Note

Given these settings, the `IVCharacteristics` study object will do a scan over the gate-source voltage values from

$$V_{gs0} = -0.3\text{V to}$$

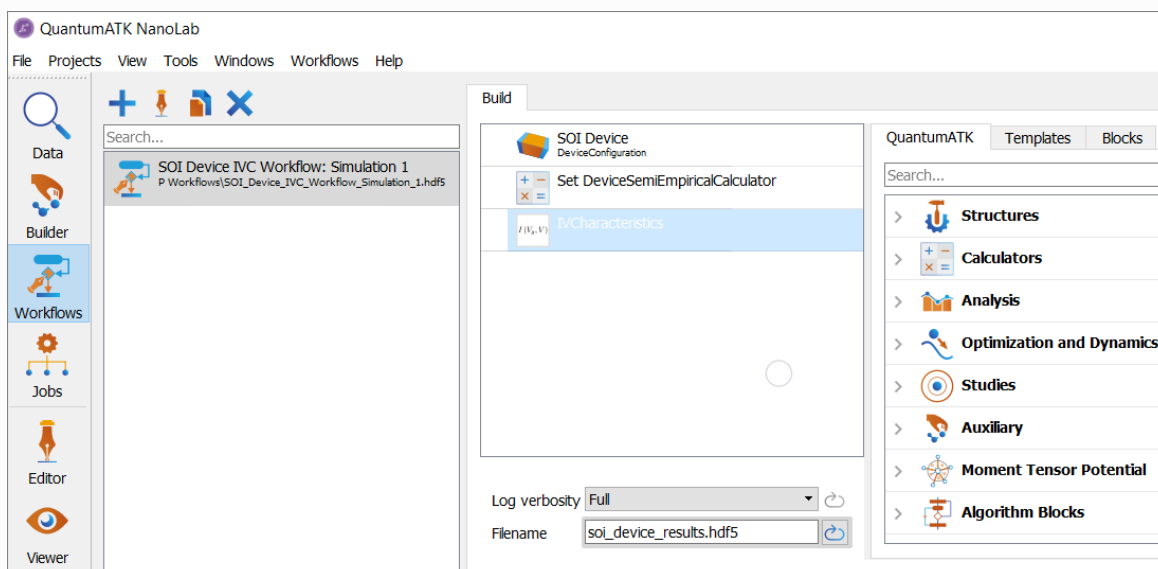
$$V_{gs1} = 0.0\text{V, at regular intervals of}$$


$$\Delta V_{gs} = 0.05\text{V and at a small drain-source bias voltage applied,}$$

$$V_{ds} = 0.05\text{V.}$$





Using a predefined Workflow



To verify if the *SOI Device* workflow in the previous section is created correctly, one can compare it to a predefined workflow, which can be downloaded at [Workflow 1](#). To use the predefined workflow, one should place the corresponding workflow (hdf5) file in your project folder in the *Workflows* subfolder (create it, if missing), and it will then appear in the **Workflow Builder** window of the **QuantumATK NanoLab GUI** as follows.



The *SOI Device* workflow created in the previous section and predefined *SOI Device IVC Workflow: Simulation 1* are supposed to be identical. Rename the *SOI Device* workflow to *SOI Device IVC Workflow: Simulation 1* in the  **Workflow Builder** window.

Running Workflows

To run the *SOI Device IVC Workflow: Simulation 1*, send it to the  **Job manager** using the  button, saving it, e.g., with a default filename '*soi_device_results.py*'. When submitting it to a *Local Machine*, then you might also need pressing the  button in the  **Job manager** to actually start running the calculation. This device calculation will take about 5 minutes using 40 MPI processes.

Once the device calculation is done (or started), go to the  **Data View** (or to the working directory on a remote machine) and click on the log file `soi_device_results.log` in the *Data View* window (or use a text editor on the remote machine) to view the log information in the  **Editor**. A list of all the planned tasks that are to be done by the `IVCharacteristics` study object can then be seen in the log, see the following figure with the first 3 (out of 14) workflow tasks highlighted in yellow.

```

1 +-----+
2 | IV Characteristics Study |
3 +-----+
4 | 14 task(s) will be executed. |
5 | |
6 | * Update configuration |
7 | Gate voltage: -0.3 V |
8 | Left electrode voltage: 0.0 V |
9 | Right electrode voltage: 0.05 V |
10 | * Update configuration |
11 | Gate voltage: -0.25 V |
12 | Left electrode voltage: 0.0 V |
13 | Right electrode voltage: 0.05 V |
14 | * Update configuration |
15 | Gate voltage: -0.2 V |

```

During the workflow execution, an additional information box will be printed out to the main log file for each started task of the workflow. In the following example of the main log file, there are 14 tasks to be executed, *task 1* is finished and *task 2* is in progress.

```

1 +-----+
2 | Executing task 1 / 14: |
3 | Update configuration |
4 | Gate voltage: 0.0 V |
5 | Left electrode voltage: 0.0 V |
6 | Right electrode voltage: 0.05 V |
7 | Log to: iv_characteristics_Vgs_0.0_Volt_Vds_0.05_Volt.log |
8 +-----+
9 +-----+
10 | Executing task 2 / 14: |
11 | Calculate TransmissionSpectrum |
12 | Gate voltage: 0.0 V |
13 | Left electrode voltage: 0.0 V |
14 | Right electrode voltage: 0.05 V |
15 | Log to: iv_characteristics_Vgs_0.0_Volt_Vds_0.05_Volt.log |
16 +-----+

```

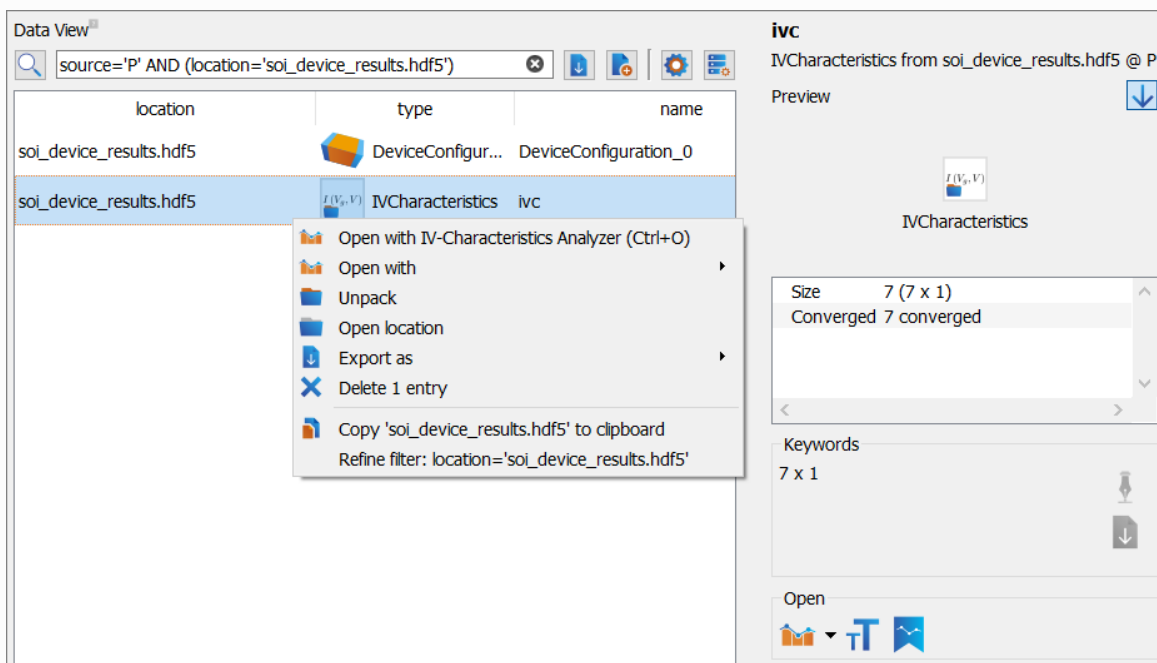
Note

For each gate voltage point, the study object will create an additional log file with the usual NEGF-SCF convergence information, as well as information on related analysis object calculations, e.g., on the *Transmission Spectrum* calculation. We will not discuss that in more detail here.

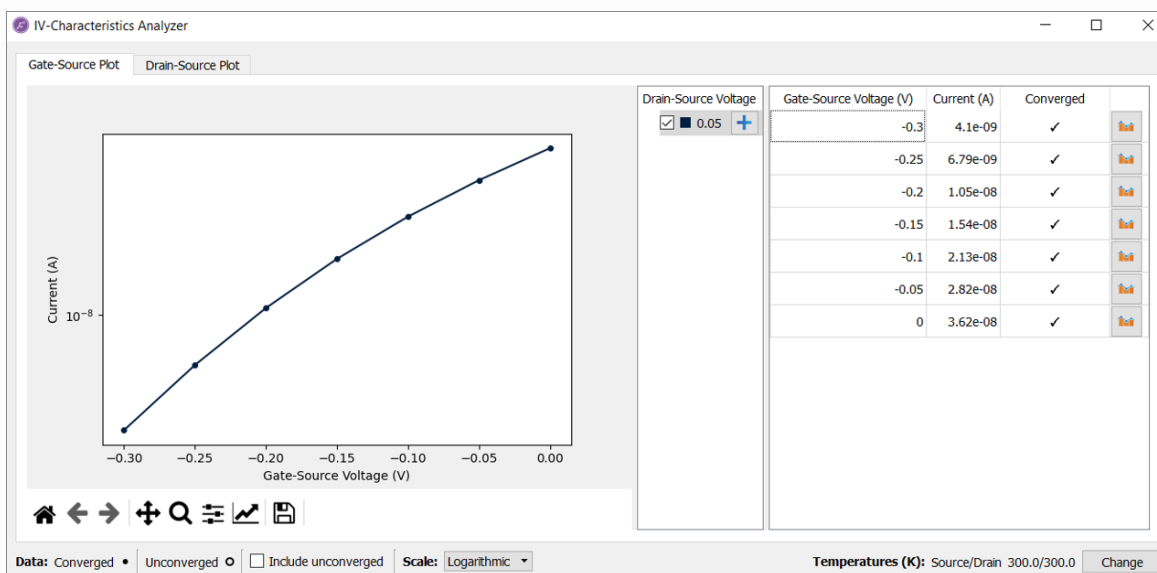
Analyzing the Workflow results

Close the **Editor** and go back to the **Data View** of the **QuantumATK NanoLab GUI**. In the *Data Sources*, select the file `soi_device_results.hdf5` and then click on (or right-click to Open with) the

$I(V_g, V)$ *IVCharacteristics* object in the *Data View* window to open the object, e.g., to view it with the *IV-Characteristics Analyzer*.



The *IV-Characteristics Analyzer* widget will then appear as follows.



The bottom part of the *IV-Characteristics Analyzer* widget contains the following supplemental information:

- **Data:** the convergence information for individual self-consistent device calculations at different voltages. In this case all bias points are converged.

Note

An unconverged point in the

I_{ds} vs. V_{gs} data set means that the NEGF-SCF calculation did not reach the target convergence parameter value (which is set in the *Device Calculator*) for the corresponding gate voltage value and are thus unreliable. For tips on how to reach the convergence target, see the guidelines in the [NEGF Convergence Guide](#).

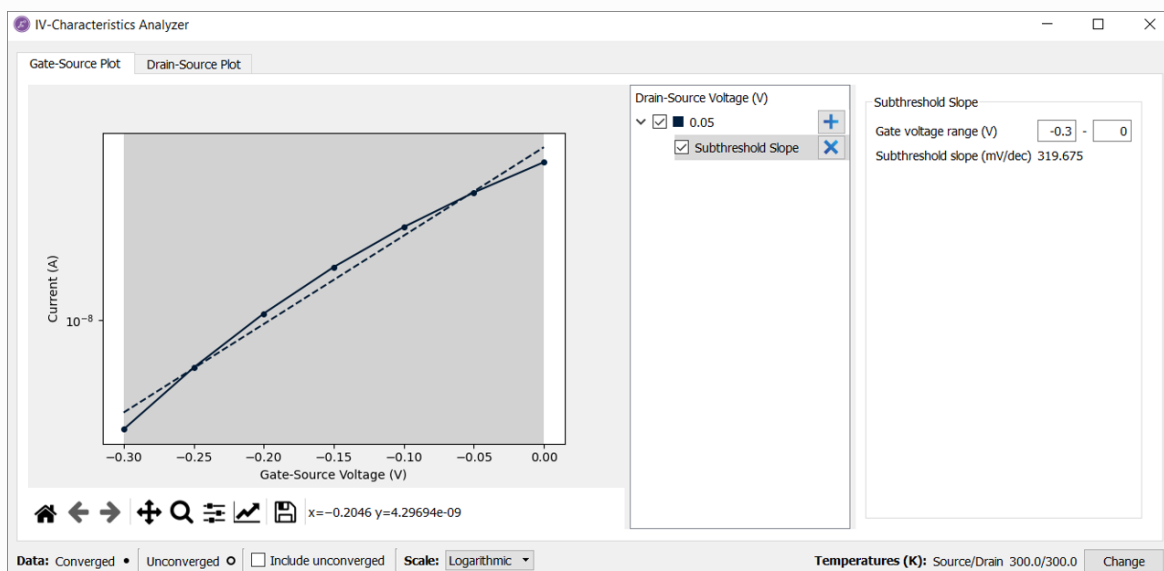
- **Scale:** the plotting scale used on the Y-axis for the drain-source current I_{ds} , which can be viewed as either *Linear* or *Logarithmic*.
- **Temperatures:** the electron temperature in the electrodes adopted to calculate the drain-source current I_{ds} , using the [TransmissionSpectrum](#) calculated by the [IVCharacteristics](#) study object. Note that the temperature for each electrode can be modified by the user, and the current is then re-calculated accordingly.

The top part of the *IV-Characteristics Analyzer* shows the actual plots of the [IVCharacteristics](#) data, allowing one to switch between two different types of visualization:

- **Gate-Source Plot** of the drain-source current vs. the gate-source voltage (I_{ds} vs. V_{gs} curve),
- **Drain-Source Plot** of the drain-source current vs. the drain-source voltage (I_{ds} vs. V_{ds} curve).

Given that a single bias voltage V_{ds} has been considered in this *Workflow 1*, only the I_{ds} vs. V_{gs} characteristics will be analyzed at this time.

To calculate relevant characteristics of the FET device, e.g., the subthreshold slope SS, click on the **+** button in the *Drain-Source Voltage* section at the center of the panel and select the *Subthreshold Slope* option from the drop-down menu. The *Gate voltage range* over which the SS is calculated will be highlighted in gray in the I_{ds} vs. V_{gs} plot. You can adjust this range to calculate the SS in the *Subthreshold Slope* panel on the right-hand side of the screen.



Note

For the obtained I_{ds} — V_{ds} curve, the value of SS is highly overestimated. The SS value is also very sensitive to the actual choice of the *Gate voltage range*. This is because the curve section, which is used to compute the SS parameter here, lies outside the subthreshold region / FET off-state. In the latter, the current



I_{ds} is supposed to vary linearly (on a logarithmic scale) with V_{gs} . For a reliable calculation of the SS, the range of V_{gs} voltage values must therefore be extended to the subthreshold region, or, in other words, to the FET off-state, as done in the following section.

Extending the range of the $I_{ds} - V_{gs}$ curve to the FET off-state

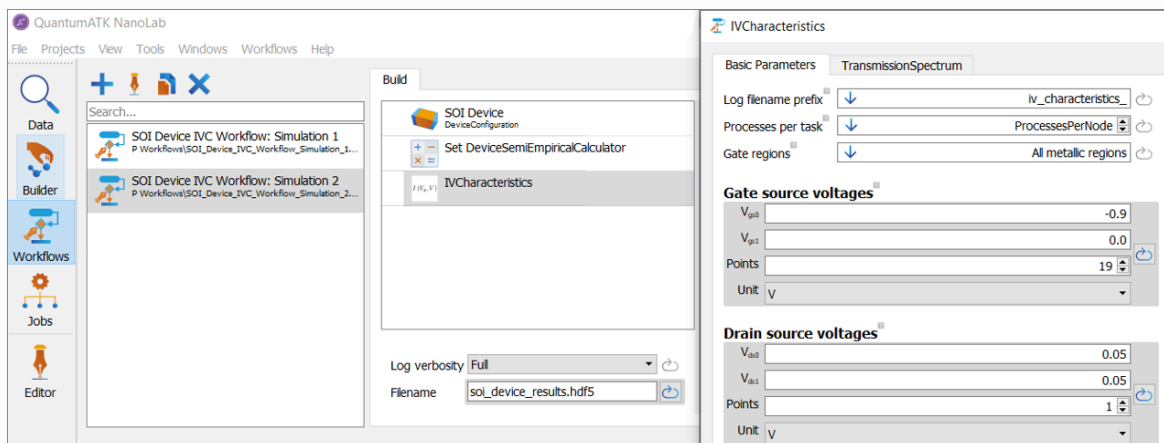
To sample the subthreshold region for the SOI FET device considered, the range of V_{gs} has to be extended to $-0.9V \leq V_{gs} \leq 0.0V$. This can be achieved in two ways:

- 2A. Extending the gate-source voltage range through the QuantumATK NanoLab GUI in the Workflow Builder
- 2B. Use scripting to add data points to the IVCharacteristics study object

2A. Extending the gate-source voltage range through the QuantumATK NanoLab GUI in the Workflow Builder




To extend the gate-source voltage range in the *Workflow*, one can select the *SOI Device IVC Workflow: Simulation 1* (described in [Section 1](#)) and copy it with the  *Duplicate* button, rename it to the *SOI Device IVC Workflow: Simulation 2* in the  **Workflow Builder** window to then modify the **Gate source voltage** range settings in the **IVCharacteristics** study object as follows:

- Set the lower limit to $V_{gs0} = -0.9V$,
- Set the number of voltage points to 19 to also include the original gate voltage range (for the on-state), $-0.3V \leq V_{gs} \leq 0.0V$, see also a note in the following.



Note

For the sake of comparison, the predefined *SOI Device IVC Workflow: Simulation 2* is enclosed to this tutorial and can be downloaded at [Workflow 2](#).

To do the *Workflow 2* for the extended gate voltage range, send *SOI Device IVC Workflow: Simulation 2* to the  **Job manager** using the  button, save it as `soi_device_results.py` and press the  button to run the corresponding job, if needed. The calculation will take about 5 minutes using 40 MPI processes.

Inspecting the log file of the follow-up *Workflow 2* calculation, one can notice that only the V_{gs} voltage points added to the original gate voltage range of [Section 1](#) have been calculated. It means that the `IVCharacteristics` study object automatically performs a check of which values of V_{gs} have been already considered, and run calculations only for the remaining values of V_{gs} .


It is important that:

- The output / results (hdf5) file obtained in [Section 1](#) is located in the same folder as the `soi_device_results.py` file,
- And the new output / results (hdf5) file for the *Workflow 2* calculation has the same filename as that used for the *Workflow 1* calculation in [Section 1](#). In the present example, keep the *Results file* filename as '`soi_device_results.hdf5`'.

Note



The range of the gate-source voltage values and number of voltage points have been chosen such that the gate-source voltage values in the range of $-0.3V \leq V_{gs} \leq 0.0V$ are the same as those used in the section [Section 1](#). This ensures that the study object will not repeat any calculation in that gate-source voltage range.

2B. Use scripting to add data points to the IVCharacteristics study object

There exists another option to instruct the `IVCharacteristics` study object to do calculations for additional values of V_{gs} . That can be done through Python scripting by adding the required voltage values by directly modifying the script, e.g., if the original workflow is missing or one cannot run the  QuantumATK NanoLab GUI for some reason.

Note





An extensive list of all the commands available to interact with the IVCharacteristics study object is available in the `IVCharacteristics` entry of the reference manual.

To do this, click on (or right-click to open with) the script `soi_device_results.py` in the  **Data View** window (or just open this script in some text editor) to open it the  **Editor**. Add the line highlighted in yellow in the IVCharacteristics block.



```

iv_characteristics = IVCharacteristics(
    configuration=soi_device,
    filename='soi_device_results.hdf5',
    object_id='ivc',
    gate_regions=None,
    gate_source_voltages=numpy.linspace(-0.3, 0.0, 7)*Volt,
    drain_source_voltages=numpy.linspace(0.05, 0.05, 1)*Volt,
    gate_potential_alignment=gate_potential_alignment,
    energies=None,
    kpoints=kpoints,
    kpoints_weights=None,
    self_energy_calculator=self_energy_calculator,
    energy_zero_parameter=AverageFermiLevel,
    infinitesimal=1e-06*eV,
    log_filename_prefix='iv_characteristics_',
    number_of_processes_per_task=ProcessesPerNode,
    device_transmission_method=device_transmission_method,
    enforce_zero_transmission_in_band_gap=True,
    source_electrode=Left,
    max_initial_state_configurations=3
)
iv_characteristics.addVoltages(gate_source_voltages=numpy.linspace(-0.9, -0.35, 12)*Volt)
iv_characteristics.update()

```

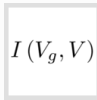
To run the device calculation, send the script to the  **Job manager** using the  button, save it as `soi_device_ivc_through_scripting.py`, and press the  button in the  **Job manager**, if needed. The calculation will take about 5 minutes on 40 MPI processes. You can also download the full script at [soi_device_ivc_through_scripting.py](#).

Note


In general, we recommend to save *Workflows* and use them in the  **Workflow Builder**, as described in [Introduction to the Workflow Builder](#). This allows for a higher flexibility in adjusting simulation settings and the simulation workflow itself, e.g., by adding new or removing old workflow steps through the  **QuantumATK NanoLab GUI** in a simpler manner than in a script.

Analysis of the $I_{ds} - V_{gs}$ curve in the subthreshold region

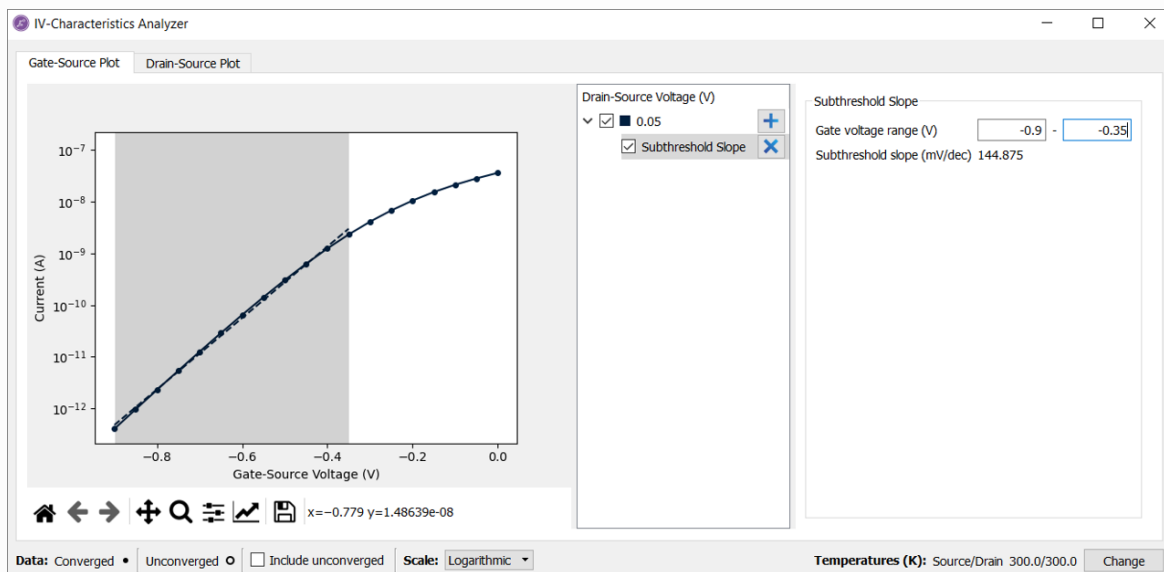
Once the device calculations are done, you are ready to analyze the characteristics of the device and extract the subthreshold slope SS, using the appropriate set of data, which includes the subthreshold region / FET off-state.

Similarly to the discussion in [Section 1](#), click on (or right-click to open with) the  $I(V_g, V)$ *IVCharacteristics* object contained in the file `soi_device_results.hdf5` present in the **Data view** window to open the *IV-Characteristics Analyzer* widget.

This time, the *IV-Characteristics Analyzer* will show an $I_{ds} - V_{gs}$ curve exhibiting a virtually linear behavior with respect to V_{gs} in the gate voltage range of $-0.9V \leq V_{gs} \leq -0.35V$. This indicates that this range of V_{gs} corresponds to the subthreshold region / FET off-state. Approximating the $I_{ds} - V_{gs}$ curve with a linear fit allows for extracting the subthreshold slope SS.

Click on the  button in the **Drain-Source Voltage** section at the center of the panel and select the *Subthreshold Slope* option from the available options in the drop-down menu. Adjust the *Gate voltage*

range in the *Subthreshold Slope* panel to include only the subthreshold region by setting it from -0.9V to -0.35V , as shown in the following figure.



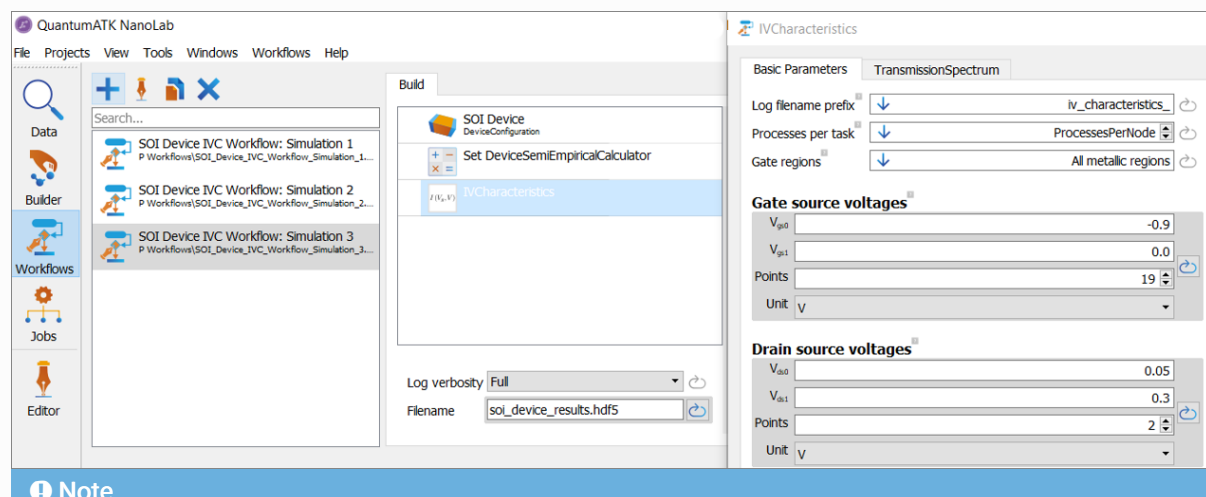
The calculated value of the subthreshold slope is now $SS = 145 \text{ meV/dec}$, being of the same order of magnitude as a measured value of $SS^{\text{exp}} = 95 \text{ meV/dec}$ [3]. The discrepancy is related to a simplified model for the SOI FET device adopted in this tutorial for the sake of basic workflow demonstration.

Calculating the drain-induced barrier lowering

To calculate the drain-induced barrier lowering (DIBL), one needs to obtain a second I_{ds} vs. V_{gs} curve at a somewhat higher value of the source-drain bias voltage, $V_{\text{ds}} = 0.3\text{V}$, for example.

To extend the range of the source-drain voltage values in the study object, one can select the *SOI Device IVC Workflow: Simulation 2* (described in Section 2A) and copy it with the *Duplicate* button, and rename it to the *SOI Device IVC Workflow: Simulation 3* in the **Workflow Builder** window to then modify the **Drain-source voltage range** settings in the **IVCharacteristics** study object as follows:

- Set the upper limit of the drain-source voltage range to $V_{\text{ds1}} = 0.3\text{V}$,
- Set the number of points to 2.



For the sake of comparison, the predefined *SOI Device IVC Workflow: Simulation 3* is enclosed to this tutorial and can be downloaded at [Workflow 3](#).

To do the *Workflow 3* for the extended gate voltage range, send *SOI Device IVC Workflow: Simulation 3* to the [Job manager](#) using the [button](#), save it as `soi_device_results.py` and press the [button](#) to run the corresponding job, if needed. The calculation will take about 10 minutes using 40 MPI processes.

It is important that:

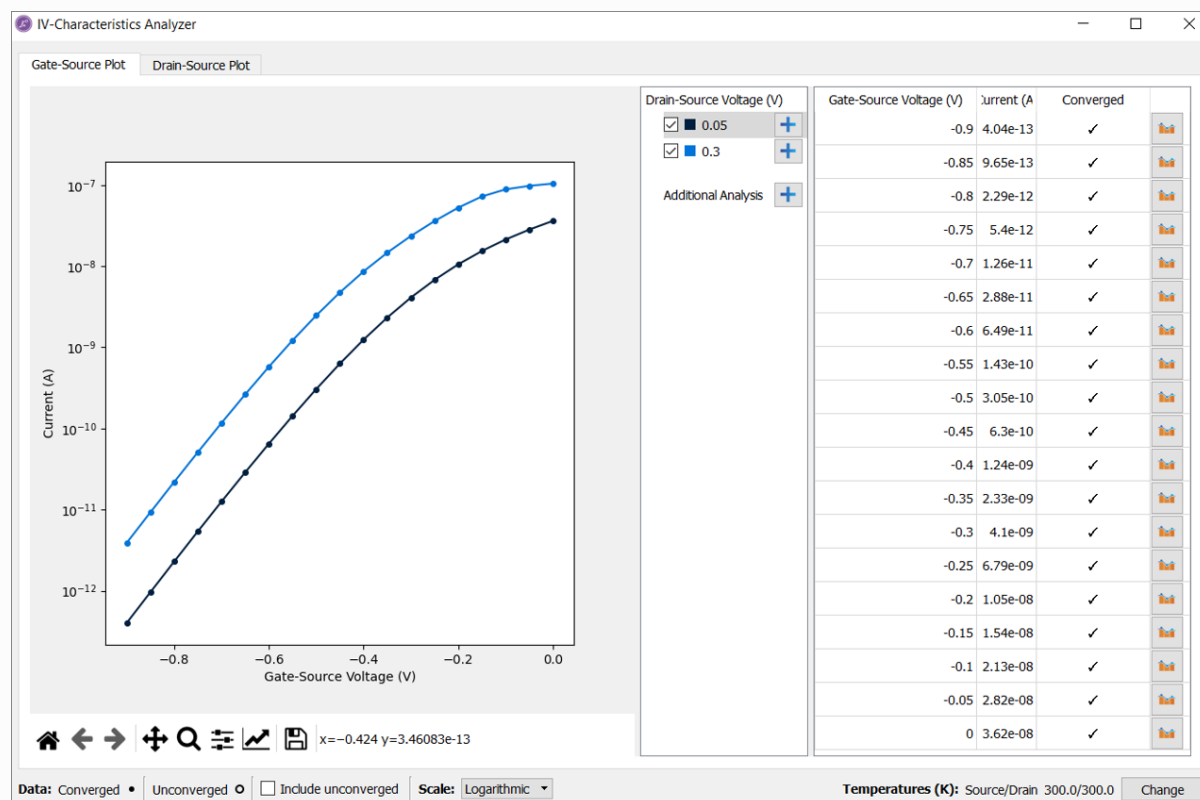
- The output / results (hdf5) file obtained in [Section 2A](#) is located in the same folder as the `soi_device_results.py` file,
- And the new output / results (hdf5) file for the *Workflow 2* calculation has the same filename as that used for the *Workflow 1* calculation in [Section 2A](#). In the present example, keep the *Results file* filename as '`soi_device_results.hdf5`'.

Note

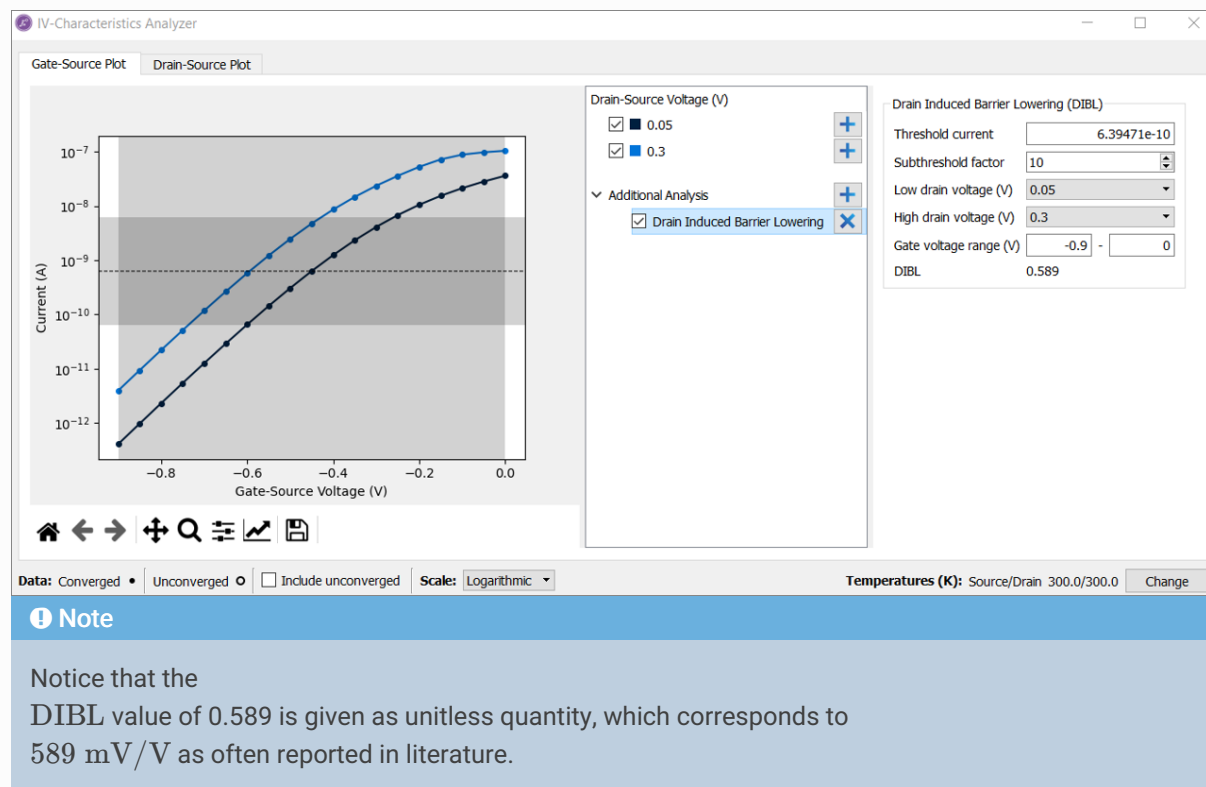
By inspecting the log file, you will notice how, thanks to the smart handling of pre-existing calculations, the **IV Characteristics** object has calculated only the curve at $V_{ds} = 0.3V$, using the points calculated at $V_{ds} = 0.05V$ as initial states until there are $V_{ds} = 0.3V$ points available.

When the calculation is done, select the `I (V_g, V)` *IVCharacteristics* object contained in the file

`soi_device_results.hdf5` in the **Workflow Builder** window, and click on the *IV-Characteristics Analyzer* plugin in the right-hand side of the **Quantum ATK NanoLab GUI window**. The *IV-Characteristics Analyzer* plugin will now show also the two additional curves calculated at $V_{ds} = 0.3V$, in addition to that previously calculated at a lower bias voltage of $V_{ds} = 0.05V$, as shown in the following figure.



To calculate the DIBL parameter, click on the **+** button next to the *Additional Analysis* option in the *Drain-Source Voltage* section at the center of the panel, and select *Drain Induced Barrier Lowering* from the drop-down menu. The calculated value of DIBL will be shown in the *Drain Induced Barrier Lowering* section, as shown in the figure below.



There are a number of parameters that can be tuned in the **Drain Induced Barrier Lowering** panel to tune the calculation of the DIBL. In particular, it is worth mentioning that:

- The *Threshold current*, which is the value of the current corresponding to a value of V_{gs} equal to the threshold voltage, is set by default at the mid-point between the maximum and the minimum values of the current I_{ds} , but can be modified by the user.
- The *Subthreshold factor* determines the current range used to fit the subthreshold characteristics of the device to accurately determine the threshold voltage. A range containing at least 3 points is then requested. If not enough points are included, the DIBL will not be calculated and an error message will be shown instead.
- The *Gate voltage range* can be modified to include only that part of the curve for which the DIBL should be calculated. This can be important for device models showing bipolar characteristics, where one has two subthreshold regions.

Warning

The value of the DIBL calculated for the FET device considered in the present tutorial is significantly larger than that measured experimentally. This can be ascribed to the high sensitivity of the DIBL parameter value to the doping profile and the geometrical characteristics of the device. For a FET device with an ultra-short metal gate length, one can expect the DIBL parameter value between 0.1 and 1, as obtained in the present example.

References

[1] (1,2)

S. M. Sze and K. N. Kwok. *Physics of Semiconductor Devices*. Wiley, 3rd edition, 2006.

[2]

T. B. Boykin, M. Luisier, M. Salmani-Jelodar, and G. Klimeck. Strain-induced, off-diagonal, same-atom parameters in empirical tight-binding theory suitable for [110] uniaxial strain applied to a silicon parametrization. *Phys. Rev. B*, 81:125202, 2010. doi:10.1103/PhysRevB.81.125202.

[3]

Shinji Migita, Yukinori Morita, Meishoku Masahara, and Hiroyuki Ota. Electrical performances of junctionless-fets at the scaling limit (lch = 3 nm). *Proceedings of the Electron Device Meeting (IEDM) 2012*, 2012. URL: <http://ieeexplore.ieee.org/document/6479006>, doi:10.1109/IEDM.2012.6479006.

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